

Title (en)

Charging method and charging equipment of diaphragm for condenser microphone

Title (de)

Verfahren zur Ladung und Ladungsgerät einer Membran eines Kondensator-Mikrofon

Title (fr)

Procédé et dispositif de charge pour diaphragme de microphone à condensateur

Publication

EP 1085783 A2 20010321 (EN)

Application

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Priority

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Abstract (en)

A charging method and equipment of a diaphragm (10) for a condenser microphone capable of charging an electric charge to the diaphragm (back plate) built in the condenser microphone, that is, a thin film made of a high polymer material having a conductive material deposited on the both sides thereof by corona discharging and ion implanting. The method comprises the steps of: supplying positive ions provided from a positive ion generating apparatus (3) and negative ions provided from a negative ion generating apparatus to a path to which a high voltage is applied to thereby form a corresponding space as an air layer of a conductive medium; and implanting electric charges formed by corona discharging upon application of the high voltage to the diaphragm to thereby form electric double layers on the thin film of the high polymer material. <IMAGE>

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